

Notice of References Cited

Application/Control No.

09/743,982

Applicant(s)/Patent Under

Reexamination

ABE ET AL.

Examiner

Matthew A. Anderson

Art Unit

1765

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5700320	12-1997	Izunome et al.	117/19
	B	US-4152536	05-1979	Ravi	136/89 sj
	C	US-5704974	01-1998	Izunome et al.	117/28
	D	US-4134785	01-1979	Lavigna et al.	156/601
	E	US-		/	
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
*	N	08-330611	12-1996	Japan	Hisamatu et al.	H01L/31/04
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Minahan et al., Conf. Rec. IEEE Photovoltaic Spec. Conf. (1982), 16 th , 310-15.
	V ₀	Wolf et al., Silicon Processing for the VLSI Era, Volume 1: Process Technology, Lattice Press, Sunset Beach, CA, USA, pp. 1-35, 1986.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
 Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.